

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**Applicant** 

Raaijmakers et al.

App. No.

: 09/452,844

Filed

: December 3, 1999

For

CONFORMAL THIN FILMS OVER

TEXTURED CAPACITOR ELECTRODES

Examiner

R. Rocchegiani

Group Art Unit

2825

## **INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing 5 references that are also enclosed. This Information Disclosure Statement is being filed concurrently with a Request for Continued Examination under 37 C.F.R. § 1.114 and no fee is believed due. The Commissioner is hereby authorized to charge any additional fees which may be required or to credit any overpayment to Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: August 14, 2003

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FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO. ASMMC.006AUS APPLICATION NO. 09/452,844

1 8 2003

TINFORMATION DISCLOSURE STATEMENT

BY APPLICANT

APPLICANT Raaijmakers et al.

December 3, 1999

**FILING DATE** 

GROUP 2825

SE SEVERAL SHEETS IF NECESSARY)

| U.S. PATENT DOCUMENTS |   |                 |          |             |       |          |                                 |  |
|-----------------------|---|-----------------|----------|-------------|-------|----------|---------------------------------|--|
| EXAMINER<br>INITIAL   |   | DOCUMENT NUMBER | DATE     | NAME        | CLASS | SUBCLASS | FILING DATE<br>(IF APPROPRIATE) |  |
|                       | 1 | 6,270,572       | 08/07/01 | Kim et al.  |       | _        |                                 |  |
|                       | 2 | 6,335,240       | 01/01/02 | Kim et al.  |       |          | -                               |  |
|                       | 3 | 5,923,056       | 07/13/99 | Lee et al.  |       |          |                                 |  |
|                       | 4 | 6,342,712       | 01/29/02 | Miki et al. |       |          |                                 |  |

| EXAMINER INITIAL | Official poddimental function in the production of the production |   |  |
|------------------|---|---|--|
|                  |   | Materro et al., "Effect of water dose on the atomic layer deposition rate of oxide thin films." Thin Solid Films 368 (2000), pgs. 1-7 |  |

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AUG 20 2003 TECHNOLOGY CENTER 2800

EXAMINER

DATE CONSIDERED